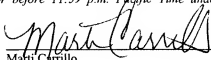


PATENT

Date of Notice
of Allowance : December 19, 2008

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

I hereby certify that this correspondence is being electronically filed with the United States Patent and Trademark Office on March 17, 2009 at or before 11:59 p.m. Pacific Time under the Rules of 37 CFR § 1.8.


Mark Carrillo

Applicant : Kim, Nam Hun Confirmation No. 5813
Application No. : 10/593,857
Filed : September 22, 2006
Title : PLASMA CHAMBER HAVING PLASMA SOURCE COIL AND
METHOD FOR ETCHING THE WAFER USING THE SAME
Grp./Div. : 1792
Examiner : Duy Vu Nguyen Deo
Docket No. : 58409/N305

COMMENTS ON STATEMENT OF REASONS FOR ALLOWANCE

Mail Stop Issue Fee
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Post Office Box 7068
Pasadena, CA 91109-7068
March 17, 2009

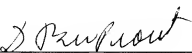
Commissioner:

Reasons for allowance are only warranted in instances in which "the record of the prosecution as a whole does not make clear his or her reasons for allowing a claim or claims."
(37 CFR § 1.104(e))

Applicant believes the Examiner's stated reasons for allowance are unnecessary. The applicant does not necessarily agree with each statement in the reasons for allowance. While applicant agrees that the claims are allowable, applicant does not acquiesce with each statement in the reasons for allowance, that patentability requires each stated feature exactly as expressed by the Examiner, nor that each stated feature is required for patentability.

Appln No. 10/593,857
Stmt date March 17, 2009

Respectfully submitted,
CHRISTIE, PARKER & HALE, LLP

By 
D. Bruce Prout
Reg. No. 20,958
626/795-9900

DBP/mac

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